

Dirch Hjorth H Petersen

List of Publications by Year in Descending Order

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Version: 2024-04-27

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The third column is the impact factor (IF) of the journal, and the fourth column is the number of citations of the article.

69
papers

1,280
citations

22
h-index

33
g-index

71
ext. papers

1,519
ext. citations

3.6
avg, IF

4
L-index

#	Paper	IF	Citations
69	Apparent size effects on dopant activation in nanometer-wide Si fins. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2021 , 39, 023202	1.3	
68	Determination of the temperature coefficient of resistance from micro four-point probe measurements. <i>Journal of Applied Physics</i> , 2021 , 129, 165105	2.5	1
67	Four-probe sensing of temperature during Joule heating of silicon. <i>Review of Scientific Instruments</i> , 2021 , 92, 014903	1.7	
66	Effective electrical resistivity in a square array of oriented square inclusions. <i>Nanotechnology</i> , 2021 , 32, 185706	3.4	2
65	π correction method for eliminating resistance measurement error due to Joule heating. <i>Review of Scientific Instruments</i> , 2021 , 92, 094711	1.7	0
64	Enhanced thermally aided memory performance using few-layer ReS ₂ transistors. <i>Applied Physics Letters</i> , 2020 , 116, 052104	3.4	5
63	Wafer-scale graphene quality assessment using micro four-point probe mapping. <i>Nanotechnology</i> , 2020 , 31, 225709	3.4	3
62	Electrical Contact Formation in Micro Four-Point Probe Measurements. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2020 , 217, 1900579	1.6	0
61	Qualitative analysis of scanning gate microscopy on epitaxial graphene. <i>2D Materials</i> , 2019 , 6, 025023	5.9	2
60	Exploring conductivity in ex-situ doped Si thin films as thickness approaches 5 nm. <i>Journal of Applied Physics</i> , 2019 , 125, 225709	2.5	7
59	Towards diamond micro four-point probes. <i>Micro and Nano Engineering</i> , 2019 , 5, 100037	3.4	0
58	Width-Dependent Sheet Resistance of Nanometer-Wide Si Fins as Measured with Micro Four-Point Probe. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2018 , 215, 1700857	1.6	6
57	Quality assessment of terahertz time-domain spectroscopy transmission and reflection modes for graphene conductivity mapping. <i>Optics Express</i> , 2018 , 26, 9220-9229	3.3	27
56	Hall effect measurement for precise sheet resistance and thickness evaluation of Ruthenium thin films using non-equidistant four-point probes. <i>AIP Advances</i> , 2018 , 8, 055206	1.5	2
55	Electrical Homogeneity Mapping of Epitaxial Graphene on Silicon Carbide. <i>ACS Applied Materials & Interfaces</i> , 2018 , 10, 31641-31647	9.5	18
54	Electrical characterization of single nanometer-wide Si fins in dense arrays. <i>Beilstein Journal of Nanotechnology</i> , 2018 , 9, 1863-1867	3	3
53	A variable probe pitch micro-Hall effect method. <i>Beilstein Journal of Nanotechnology</i> , 2018 , 9, 2032-2039		0

52	Vibration tolerance of micro-electrodes. <i>Journal of Micromechanics and Microengineering</i> , 2018 , 28, 095010	10	2
51	Graphene antidot lattice transport measurements. <i>International Journal of Nanotechnology</i> , 2017 , 14, 226	1.5	9
50	Reversible hysteresis inversion in MoS2 field effect transistors. <i>Npj 2D Materials and Applications</i> , 2017 , 1,	8.8	67
49	Breakthrough in current-in-plane tunneling measurement precision by application of multi-variable fitting algorithm. <i>Review of Scientific Instruments</i> , 2017 , 88, 095005	1.7	4
48	Mapping the electrical properties of large-area graphene. <i>2D Materials</i> , 2017 , 4, 042003	5.9	75
47	Batch fabrication of nanopatterned graphene devices via nanoimprint lithography. <i>Applied Physics Letters</i> , 2017 , 111, 193103	3.4	16
46	Quality assessment of graphene: Continuity, uniformity, and accuracy of mobility measurements. <i>Nano Research</i> , 2017 , 10, 3596-3605	10	22
45	Contactless graphene conductance measurements: the effect of device fabrication on terahertz time-domain spectroscopy. <i>International Journal of Nanotechnology</i> , 2016 , 13, 591	1.5	11
44	Mesoscopic current transport in two-dimensional materials with grain boundaries: Four-point probe resistance and Hall effect. <i>Journal of Applied Physics</i> , 2016 , 120, 134303	2.5	5
43	Atomic Layer Deposition of Ruthenium with TiN Interface for Sub-10 nm Advanced Interconnects beyond Copper. <i>ACS Applied Materials & Interfaces</i> , 2016 , 8, 26119-26125	9.5	55
42	Graphene mobility mapping. <i>Scientific Reports</i> , 2015 , 5, 12305	4.9	75
41	Characterization of positional errors and their influence on micro four-point probe measurements on a 100 nm Ru film. <i>Measurement Science and Technology</i> , 2015 , 26, 095005	2	2
40	Terahertz wafer-scale mobility mapping of graphene on insulating substrates without a gate. <i>Optics Express</i> , 2015 , 23, 30721-9	3.3	37
39	Characterization of magnetic tunnel junction test pads. <i>Journal of Applied Physics</i> , 2015 , 118, 143901	2.5	1
38	Fabrication of CVD graphene-based devices via laser ablation for wafer-scale characterization. <i>2D Materials</i> , 2015 , 2, 045003	5.9	23
37	Theoretical analysis of a dual-probe scanning tunneling microscope setup on graphene. <i>Physical Review Letters</i> , 2014 , 112, 096801	7.4	24
36	Optimized Laser Thermal Annealing on Germanium for High Dopant Activation and Low Leakage Current. <i>IEEE Transactions on Electron Devices</i> , 2014 , 61, 4047-4055	2.9	32
35	Electrically continuous graphene from single crystal copper verified by terahertz conductance spectroscopy and micro four-point probe. <i>Nano Letters</i> , 2014 , 14, 6348-55	11.5	59

34	2014,			5
33	Sensitivity of resistive and Hall measurements to local inhomogeneities: Finite-field, intensity, and area corrections. <i>Journal of Applied Physics</i> , 2014 , 116, 133706	2.5		13
32	Sensitivity analysis explains quasi-one-dimensional current transport in two-dimensional materials. <i>Physical Review B</i> , 2014 , 90,	3.3		7
31	Graphene transport properties upon exposure to PMMA processing and heat treatments. <i>2D Materials</i> , 2014 , 1, 035005	5.9		56
30	Revealing origin of quasi-one dimensional current transport in defect rich two dimensional materials. <i>Applied Physics Letters</i> , 2014 , 105, 053115	3.4		10
29	Ultra-high aspect ratio replaceable AFM tips using deformation-suppressed focused ion beam milling. <i>Nanotechnology</i> , 2013 , 24, 465701	3.4		10
28	Sensitivity of resistive and Hall measurements to local inhomogeneities. <i>Journal of Applied Physics</i> , 2013 , 114, 163710	2.5		11
27	Microprobe metrology for direct sheet resistance and mobility characterization 2012 ,			1
26	Graphene conductance uniformity mapping. <i>Nano Letters</i> , 2012 , 12, 5074-81	11.5		112
25	Junction leakage measurements with micro four-point probes 2012 ,			6
24	Fast micro Hall effect measurements on small pads. <i>Journal of Applied Physics</i> , 2011 , 110, 033707	2.5		6
23	In Situ Tuning of Focused-Ion-Beam Defined Nanomechanical Resonators Using Joule Heating. <i>Journal of Microelectromechanical Systems</i> , 2011 , 20, 1074-1080	2.5		1
22	Systematic study of shallow junction formation on germanium substrates. <i>Microelectronic Engineering</i> , 2011 , 88, 347-350	2.5		14
21	Optimization of FIB milling for rapid NEMS prototyping. <i>Microelectronic Engineering</i> , 2011 , 88, 2671-2674.	4.5		3
20	Three-way flexible cantilever probes for static contact. <i>Journal of Micromechanics and Microengineering</i> , 2011 , 21, 085003	2		4
19	Micro-cantilevers for non-destructive characterization of nanoglass uniformity 2011 ,			1
18	Ultra Shallow Arsenic Junctions in Germanium Formed by Millisecond Laser Annealing. <i>Electrochemical and Solid-State Letters</i> , 2011 , 14, H39			30
17	Electrical characterization of InGaAs ultra-shallow junctions. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2010 , 28, C1C41-C1C47	1.3		5

16	Sensitivity study of micro four-point probe measurements on small samples. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2010 , 28, C1C34-C1C40	1.3	15
15	Review of electrical characterization of ultra-shallow junctions with micro four-point probes. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2010 , 28, C1C27-C1C33	1.3	30
14	Manipulation and in situ transmission electron microscope characterization of sub-100 nm nanostructures using a microfabricated nanogripper. <i>Journal of Micromechanics and Microengineering</i> , 2010 , 20, 035009	2	17
13	Customizable in situ TEM devices fabricated in freestanding membranes by focused ion beam milling. <i>Nanotechnology</i> , 2010 , 21, 405304	3.4	11
12	Fundamental size limitations of micro four-point probes. <i>Microelectronic Engineering</i> , 2009 , 86, 987-990	2.5	12
11	Accurate microfour-point probe sheet resistance measurements on small samples. <i>Review of Scientific Instruments</i> , 2009 , 80, 053902	1.7	45
10	Electrothermal microgrippers for pick-and-place operations. <i>Microelectronic Engineering</i> , 2008 , 85, 1128-1130	1.3	27
9	Advanced carrier depth profiling on Si and Ge with micro four-point probe. <i>Journal of Vacuum Science & Technology B</i> , 2008 , 26, 317		7
8	Micro-four-point probe Hall effect measurement method. <i>Journal of Applied Physics</i> , 2008 , 104, 013710	2.5	61
7	Comparative study of size dependent four-point probe sheet resistance measurement on laser annealed ultra-shallow junctions. <i>Journal of Vacuum Science & Technology B</i> , 2008 , 26, 362		35
6	Micro Four-Point Probe with High Spatial Resolution for Ion Implantation and Ultra-Shallow Junction Characterization 2008 ,		8
5	Epitaxial integration of nanowires in microsystems by local micrometer-scale vapor-phase epitaxy. <i>Small</i> , 2008 , 4, 1741-6	11	26
4	Static contact micro four-point probes with . <i>Microelectronic Engineering</i> , 2008 , 85, 1092-1095	2.5	24
3	Topology optimized electrothermal polysilicon microgrippers. <i>Microelectronic Engineering</i> , 2008 , 85, 1096-1099	2.5	31
2	Accurate Sheet Resistance Measurement on Ultra-Shallow Profiles. <i>Materials Research Society Symposia Proceedings</i> , 2006 , 912, 1		19
1	Study of the Roughness in a Photoresist Masked, Isotropic, SF ₆ -Based ICP Silicon Etch. <i>Journal of the Electrochemical Society</i> , 2006 , 153, G1051	3.9	21